ABSTRACT OF THE DISCLOSURE

A SUBSTRATE COOLING UNIT AND THE SUBSTRATE TREATING FACILITY

Provided is a substrate cooling unit. The substrate cooling unit for cooling a substrate processed at a high temperature, includes a housing having a space therein, a cooling plate supporting the substrate within the housing, the cooling plate having a cooling passage therein through which a cooling fluid flows, and a cooling gas supply part supplying a cooling gas into the housing.

Fig. 1

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